

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Prior Application: Y. KAWAMURA et al  
Serial No. 09/754,193  
Filed: January 5, 2001

Group Art: 3723  
Examiner: M. Rachuba  
For: METHOD FOR POLISHING SURFACE OF  
SEMICONDUCTOR DEVICE SUBSTRATE

**PRELIMINARY AMENDMENT**

Commissioner for Patents  
Mail Stop Patent Application  
Alexandria, VA 22313-1450

Sir:

Prior to examination, please amend the above-identified  
application as follows.